

IVPS100 - Improved Vertical Parallel Structure

Tip width characterizer with an array of 5 lines with vertical, parallel sidewalls (111-crystal planes).

Specifications

Material	Silicon
Width of line	100 nm actual linewidth is delivered for each chip
Pitch	500 nm \pm 10nm
Depth of line	\sim 1 μ m
Surface/sidewall angle	$< 90^\circ \pm 0,5^\circ$
Sidewall parallelity	$< 1^\circ$
Top corner radius	< 10 nm

Also well suited as SEM standard

Probe tip characterizers are used to check the shape and the dimension of the probe tip.

Each cell is numbered, which facilitates recalibration at the identical position.

Layout:

81 cells on 1 x 1 mm area, on 6 x 6 mm silicon chip